

AF-Ifw

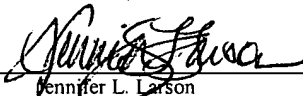
PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant:	Bruce et al.	Examiner:	Turner, S.
Serial No.:	09/386,112	Group Art Unit:	2877
Filed:	August 30, 1999	Docket No.:	AMDA.261PA (TT2335)
Title:	Dual-Differential Interferometry For Silicon Device Damage Detection		

CERTIFICATE UNDER 37 CFR 1.8: The undersigned hereby certifies that this correspondence and the papers, as described hereinabove, are being deposited in the United States Postal Service, as first class mail, in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on May 6, 2005.

By:

  
Jennifer L. Larson

**AMENDMENT AND RESPONSE TO EXAMINER'S COMMUNICATION  
AFTER DECISION ON APPEAL**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Customer No.  
**40581**

Dear Sir:

In response to the Examiner's communication dated April 13, 2005, please consider the following amendment and remarks.

Amendments to the claims are reflected in the listing of claims beginning at page 2 and the Remarks begin on page 5.